IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

BISSCHOPS

Application No.: C ntinuation of

Appln. No. 09/919,616

Group Art Unit: UNKNOWN

Filed: August 11, 2003

Examiner: UNKNOWN

Title:

LITHOGRAPHIC APPARATUS, DEVICE MANUFACTURING METHOD,

AND DEVICE MANUFACTURED THEREBY

August 11, 2003

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Attached is Form PTO-1449 listing all of the documents cited by Applicants and the PTO in the parent application No. 09/919,616 relied upon under 35 USC §120. Pursuant to Rule 98(d), copies of these documents are <u>not required</u> now.

Please consider these documents and <u>advise</u> that they have been considered in <u>this new</u> application as by returning a copy of the enclosed Form PTO-1449 with the Examiner's initials in the left column per MPEP 609.

Respectfully submitted,

PILLSBURY WINTHROP LLP

Robert C. Perez Reg. No. 39,328

Tel: (703) 905-2159 Fax: (703) 905-2500

P.O. BOX 10500 McLean, VA 22102 Tel. (703) 905.2000

FORM PTO-1449 (modified) To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office								Atty. Dkt. No.	M#		Client	Client Ref.			
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